

Resource Summary Report

Generated by RRID on Aug 8, 2026

Rigaku: TXRF 3800e

RRID:SCR_020490

Type: Tool

Proper Citation

Rigaku: TXRF 3800e (RRID:SCR_020490)

Resource Information

URL: <https://www.rigaku.com/products/semi/txrf3800e>

Proper Citation: Rigaku: TXRF 3800e (RRID:SCR_020490)

Description: Surface contamination metrology that measures elemental contamination at discrete points or with full wafer maps.

Resource Type: instrument resource

Keywords: Rigaku, Semiconductor Metrology, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: Rigaku: TXRF 3800e

Resource ID: SCR_020490

Alternate IDs: Model_Number_TXRF 3800e

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260801T190648+0000

Ratings and Alerts

No rating or validation information has been found for Rigaku: TXRF 3800e.

No alerts have been found for Rigaku: TXRF 3800e.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.